

# Christian A Zorman

## List of Publications by Year in descending order

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181  
papers

6,061  
citations

101496

36  
h-index

79644

73  
g-index

183  
all docs

183  
docs citations

183  
times ranked

5744  
citing authors

#	ARTICLE	IF	CITATIONS
1	Nanodevice motion at microwave frequencies. <i>Nature</i> , 2003, 421, 496-496.	13.7	505
2	Evaluation of MEMS materials of construction for implantable medical devices. <i>Biomaterials</i> , 2002, 23, 2737-2750.	5.7	409
3	Silicon carbide MEMS for harsh environments. <i>Proceedings of the IEEE</i> , 1998, 86, 1594-1609.	16.4	393
4	Polytype control of spin qubits in silicon carbide. <i>Nature Communications</i> , 2013, 4, 1819.	5.8	292
5	SiC MEMS: opportunities and challenges for applications in harsh environments. <i>Thin Solid Films</i> , 1999, 355-356, 518-524.	0.8	267
6	Monocrystalline silicon carbide nanoelectromechanical systems. <i>Applied Physics Letters</i> , 2001, 78, 162-164.	1.5	263
7	Wearable sensors for monitoring the physiological and biochemical profile of the athlete. <i>Npj Digital Medicine</i> , 2019, 2, 72.	5.7	235
8	Epitaxial growth of 3C-SiC films on 4 in. diam (100) silicon wafers by atmospheric pressure chemical vapor deposition. <i>Journal of Applied Physics</i> , 1995, 78, 5136-5138.	1.1	234
9	High-Temperature Single-Crystal 3C-SiC Capacitive Pressure Sensor. <i>IEEE Sensors Journal</i> , 2004, 4, 464-470.	2.4	194
10	Low Voltage Nanoelectromechanical Switches Based on Silicon Carbide Nanowires. <i>Nano Letters</i> , 2010, 10, 2891-2896.	4.5	163
11	Wearable sensors for monitoring the internal and external workload of the athlete. <i>Npj Digital Medicine</i> , 2019, 2, 71.	5.7	150
12	Silicon carbide for microelectromechanical systems. <i>International Materials Reviews</i> , 2000, 45, 85-108.	9.4	132
13	Fabrication and testing of bulk micromachined silicon carbide piezoresistive pressure sensors for high temperature applications. <i>IEEE Sensors Journal</i> , 2006, 6, 316-324.	2.4	101
14	Electrothermal tuning of Al-SiC nanomechanical resonators. <i>Nanotechnology</i> , 2006, 17, 1506-1511.	1.3	96
15	Micro- and nanomechanical structures for silicon carbide MEMS and NEMS. <i>Physica Status Solidi (B): Basic Research</i> , 2008, 245, 1404-1424.	0.7	93
16	Mechanically adaptive nanocomposites for neural interfacing. <i>MRS Bulletin</i> , 2012, 37, 581-589.	1.7	91
17	Tuning Optical Signatures of Single- and Few-Layer MoS <sub>2</sub> by Blown-Bubble Bulge Straining up to Fracture. <i>Nano Letters</i> , 2017, 17, 4568-4575.	4.5	79
18	Quantitative evaluation of biaxial strain in epitaxial 3C-SiC layers on Si(100) substrates by Raman spectroscopy. <i>Journal of Applied Physics</i> , 2002, 91, 1113-1117.	1.1	77

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19	Examination of Bulge Test for Determining Residual Stress, Young's Modulus, and Poisson's Ratio of 3C-SiC Thin Films. <i>Journal of Aerospace Engineering</i> , 2003, 16, 46-54.	0.8	77
20	Fabrication and testing of micromachined silicon carbide and nickel fuel atomizers for gas turbine engines. <i>Journal of Microelectromechanical Systems</i> , 1999, 8, 251-257.	1.7	68
21	Deposition of Polycrystalline 3C-SiC Films on 100 mm Diameter Si(100) Wafers in a Large-Volume LPCVD Furnace. <i>Electrochemical and Solid-State Letters</i> , 2002, 5, G99.	2.2	63
22	Review of Inkjet Printing of Metal Structures for Electrochemical Sensor Applications. <i>Journal of the Electrochemical Society</i> , 2020, 167, 037571.	1.3	63
23	SiC cantilever resonators with electrothermal actuation. <i>Sensors and Actuators A: Physical</i> , 2006, 128, 376-386.	2.0	62
24	Fabrication and characterization of polycrystalline SiC resonators. <i>IEEE Transactions on Electron Devices</i> , 2002, 49, 2323-2332.	1.6	60
25	Pendeo-epitaxial growth of thin films of gallium nitride and related materials and their characterization. <i>Journal of Crystal Growth</i> , 2001, 225, 134-140.	0.7	57
26	Fabrication and testing of surface micromachined polycrystalline SiC micromotors. <i>IEEE Electron Device Letters</i> , 2000, 21, 164-166.	2.2	54
27	Use of deposition pressure to control residual stress in polycrystalline SiC films. <i>Applied Physics Letters</i> , 2004, 84, 341-343.	1.5	51
28	Polycrystalline 3C-SiC thin films deposited by dual precursor LPCVD for MEMS applications. <i>Sensors and Actuators A: Physical</i> , 2005, 119, 169-176.	2.0	48
29	Characterization of polycrystalline silicon carbide films grown by atmospheric pressure chemical vapor deposition on polycrystalline silicon. <i>Journal of Materials Research</i> , 1998, 13, 406-412.	1.2	45
30	Femtosecond pulsed laser micromachining of single crystalline 3C-SiC structures based on a laser-induced defect-activation process. <i>Journal of Micromechanics and Microengineering</i> , 2003, 13, 680-685.	1.5	45
31	Mechanical properties of epitaxial 3C silicon carbide thin films. <i>Journal of Microelectromechanical Systems</i> , 2005, 14, 664-672.	1.7	45
32	Measurement of residual stress and elastic modulus of polycrystalline 3C-SiC films deposited by low-pressure chemical vapor deposition. <i>Thin Solid Films</i> , 2005, 492, 195-202.	0.8	41
33	Characterization of frequency tuning using focused ion beam platinum deposition. <i>Journal of Micromechanics and Microengineering</i> , 2007, 17, 213-219.	1.5	40
34	Stable secondary electron emission observations from chemical vapor deposited diamond. <i>Applied Physics Letters</i> , 1994, 65, 2702-2704.	1.5	39
35	Surface micromachining of polycrystalline SiC films using microfabricated molds of SiO <sub>2</sub> and polysilicon. <i>Journal of Microelectromechanical Systems</i> , 1999, 8, 237-242.	1.7	39
36	Fabrication of Electrically Conductive Metal Patterns at the Surface of Polymer Films by Microplasma-Based Direct Writing. <i>ACS Applied Materials &amp; Interfaces</i> , 2014, 6, 3099-3104.	4.0	38

#	ARTICLE	IF	CITATIONS
37	The mechanical properties of polycrystalline 3C-SiC films grown on polysilicon substrates by atmospheric pressure chemical-vapor deposition. <i>Journal of Applied Physics</i> , 2006, 99, 044108.	1.1	36
38	Vascular Pressure-Flow Measurement Using CB-PDMS Flexible Strain Sensor. <i>IEEE Transactions on Biomedical Circuits and Systems</i> , 2019, 13, 1451-1461.	2.7	36
39	Conventional and pendeo-epitaxial growth of GaN(0001) thin films on Si(111) substrates. <i>Journal of Crystal Growth</i> , 2001, 231, 335-341.	0.7	35
40	Mechanical properties of a 3C-SiC film between room temperature and 600°C. <i>Journal Physics D: Applied Physics</i> , 2007, 40, 3335-3342.	1.3	35
41	Stable secondary electron emission from chemical vapor deposited diamond films coated with alkali-halides. <i>Applied Physics Letters</i> , 1995, 66, 242-244.	1.5	34
42	Ultrawide Band Gap $\text{Ga}_2\text{O}_3$ Nanomechanical Resonators with Spatially Visualized Multimode Motion. <i>ACS Applied Materials &amp; Interfaces</i> , 2017, 9, 43090-43097.	4.0	30
43	Surface Micromachining of Polycrystalline SiC Deposited on $\text{SiO}_2$ by APCVD. <i>Materials Science Forum</i> , 1998, 264-268, 885-888.	0.3	29
44	Mid-infrared metamaterial based on perforated SiC membrane: engineering optical response using surface phonon polaritons. <i>Applied Physics A: Materials Science and Processing</i> , 2007, 88, 605-609.	1.1	29
45	Diamond-on-Polymer Microelectrode Arrays Fabricated Using a Chemical Release Transfer Process. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 867-875.	1.7	29
46	Synthesis of Wide Bandgap $\text{Ga}_2\text{O}_3$ Rods on 3C-SiC-on-Si. <i>Crystal Growth and Design</i> , 2016, 16, 511-517.	1.4	29
47	A New Class of Low-Temperature Plasma-Activated, Inorganic Salt-Based Particle-Free Inks for Inkjet Printing Metals. <i>Advanced Materials Technologies</i> , 2019, 4, 1900119.	3.0	29
48	Etching of 3C-SiC using $\text{CHF}_3/\text{O}_2$ and $\text{CHF}_3/\text{O}_2/\text{He}$ plasmas at 1.75 Torr. <i>Journal of Vacuum Science &amp; Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1998, 16, 536.	1.6	25
49	Plasmas for additive manufacturing. <i>Plasma Processes and Polymers</i> , 2020, 17, 2000009.	1.6	24
50	Origin of the split Si-H stretch mode on hydrogen terminated 6H-SiC(0001): Titration of crystal truncation. <i>Applied Physics Letters</i> , 2002, 80, 4726-4728.	1.5	23
51	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part II: electrical testing and material property extraction. <i>Journal of Microelectromechanical Systems</i> , 2005, 14, 579-589.	1.7	22
52	Electrically Conductive, Reduced Graphene Oxide Structures Fabricated by Inkjet Printing and Low Temperature Plasma Reduction. <i>Advanced Materials Technologies</i> , 2019, 4, 1900834.	3.0	22
53	Fabrication of low defect density 3C-SiC on $\text{SiO}_2$ structures using wafer bonding techniques. <i>Journal of Electronic Materials</i> , 1998, 27, L17-L20.	1.0	21
54	Pendeo-epitaxial growth of gallium nitride on silicon substrates. <i>Journal of Electronic Materials</i> , 2000, 29, 306-310.	1.0	21

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55	Development of Nickel Wire Bonding for High-Temperature Packaging of SiC Devices. IEEE Transactions on Advanced Packaging, 2009, 32, 564-574.	1.7	21
56	Micro/Nanotribological Studies of Single-Crystal Silicon and Polysilicon and SiC Films for Use in MEMS Devices. , 1998, , 407-430.		21
57	Performance of 3C-SiC thin films as protective coatings for silicon-micromachined atomizers. Thin Solid Films, 1998, 315, 170-178.	0.8	20
58	Development of a Multilayer SiC Surface Micromachining Process with Capabilities and Design Rules Comparable to Conventional Polysilicon Surface Micromachining. Materials Science Forum, 2002, 389-393, 755-758.	0.3	19
59	An oversampled capacitance-to-voltage converter IC with application to time-domain characterization of MEMS resonators. IEEE Sensors Journal, 2005, 5, 1353-1361.	2.4	19
60	Deep level defects and carrier removal due to proton and alpha particle irradiation of InP. Journal of Applied Physics, 1994, 75, 3187-3189.	1.1	18
61	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part I: growth study and device fabrication. Journal of Microelectromechanical Systems, 2005, 14, 567-578.	1.7	18
62	Amorphous SiC as a structural layer in microbridge-based RF MEMS switches for use in software-defined radio. Solid-State Electronics, 2008, 52, 1647-1651.	0.8	18
63	Atmospheric-Pressure Plasma Reduction of Metal Cation-Containing Polymer Films to Produce Electrically Conductive Nanocomposites by an Electrodiffusion Mechanism. Plasma Chemistry and Plasma Processing, 2016, 36, 295-307.	1.1	18
64	Fabrication of a Silver-Based Thermistor on Flexible, Temperature-Sensitive Substrates Using a Low-Temperature Inkjet Printing Technique. , 2019, 3, 1-4.		18
65	Nanoparticle based simple electrochemical biosensor platform for profiling of protein-nucleic acid interactions. Talanta, 2019, 195, 46-54.	2.9	18
66	Roughness Reduction of 3C-SiC Surfaces Using SiC-Based Mechanical Polishing Slurries. Journal of the Electrochemical Society, 1999, 146, 327-330.	1.3	17
67	Silicon carbide MEMS-resonator-based oscillator. Journal of Micromechanics and Microengineering, 2009, 19, 115027.	1.5	17
68	Molecular conformation and filtration properties of anionic Ficoll. American Journal of Physiology - Renal Physiology, 2010, 299, F752-F757.	1.3	17
69	Low Stress Polycrystalline SiC Thin Films Suitable for MEMS Applications. Journal of the Electrochemical Society, 2011, 158, H675-H680.	1.3	16
70	Microplasma-Induced In Situ Formation of Patterned, Stretchable Electrical Conductors. ACS Macro Letters, 2017, 6, 194-199.	2.3	16
71	Chemical Mechanical Polishing of Cubic Silicon Carbide Films Grown on Si(100) Wafers. Journal of the Electrochemical Society, 2002, 149, G643.	1.3	15
72	Electrically small folded slot antenna utilizing capacitive loaded slot lines. , 2008, , .		15

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73	Basal lamina secreted by MDCK cells has size- and charge-selective properties. American Journal of Physiology - Renal Physiology, 2011, 300, F86-F90.	1.3	15
74	Electrical Characterization of Microelectromechanical Silicon Carbide Resonators. Sensors, 2008, 8, 5759-5774.	2.1	14
75	Surface Roughness Control of 3C-SiC Films during the Epitaxial Growth Process. Journal of the Electrochemical Society, 2004, 151, G910.	1.3	13
76	Tunable resistivity in ink-jet printed electrical structures on paper by plasma conversion of particle-free, stabilizer-free silver inks. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2018, 36, 051302.	0.9	13
77	Modelling of HREM and nanodiffraction for dislocation kinks and core reconstruction. Journal of Physics Condensed Matter, 2000, 12, 10175-10183.	0.7	12
78	Fabrication of Suspended Nanomechanical Structures from Bulk 6H-SiC Substrates. Materials Science Forum, 2004, 457-460, 1531-1536.	0.3	12
79	Transfer Printing of Self-Folding Polymer-Metal Bilayer Particles. ACS Applied Materials & Interfaces, 2014, 6, 22695-22700.	4.0	12
80	Electric Field Patterning of Organic Nanoarchitectures with Self-Assembled Molecular Fibers. Journal of Physical Chemistry C, 2008, 112, 12081-12084.	1.5	11
81	Adhesion and moisture barrier characteristics of roller-cast polydimethylsiloxane encapsulants for implantable microsystems. , 2012, 2012, 1-4.		11
82	Vascular Graft Pressure-Flow Monitoring Using 3D Printed MWCNT-PDMS Strain Sensors. , 2018, 2018, 2989-2992.		11
83	$\text{Ga}_{2\text{O}_3}$ NEMS Oscillator for Real-Time Middle Ultraviolet (MUV) Light Detection. IEEE Electron Device Letters, 2018, 39, 1230-1233.	2.2	11
84	Non-hermetic packaging of biomedical microsystems from a materials perspective: A review. Medical Devices & Sensors, 2020, 3, e10082.	2.7	11
85	Electrostatically Driven Touch-Mode Poly-SiC Microspeaker. , 2007, , .		10
86	Determination of Young's moduli of 3C (110) single-crystal and (111) polycrystalline silicon carbide from operating frequencies. Journal of Materials Science, 2008, 43, 4512-4517.	1.7	10
87	The influence of impurities and planar defects on the infrared properties of silicon carbide films. Applied Physics Letters, 2011, 98, 191904.	1.5	10
88	Wireless bladder pressure monitor for closed-loop bladder neuromodulation. , 2016, 2016, .		10
89	Growth of polycrystalline SiC films on SiO <sub>2</sub> and Si <sub>3</sub> N <sub>4</sub> by APCVD. Thin Solid Films, 1999, 355-356, 179-183.	0.8	9
90	Surface Micromachining: A Brief Introduction. MRS Bulletin, 2001, 26, 289-290.	1.7	9

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91	Development of PECVD SiC for MEMS Using 3MS as the Precursor. Materials Research Society Symposia Proceedings, 2006, 911, 28.	0.1	9
92	RF MEMS switches with sic microbridges for improved reliability. , 2008, , .		9
93	Microscale Characterization of a Mechanically Adaptive Polymer Nanocomposite With Cotton-Derived Cellulose Nanocrystals for Implantable BioMEMS. Journal of Microelectromechanical Systems, 2014, 23, 774-784.	1.7	9
94	Synthesis and characterization of Ga <sub>2</sub> O <sub>3</sub> nanosheets on 3C-SiC-on-Si by low pressure chemical vapor deposition. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2017, 35, 011208.	0.6	9
95	PECVD Silicon Carbide as a Chemically-Resistant Thin Film Packaging Technology for Microfabricated Antennas. , 2006, , .		8
96	A Programmable Sustaining Amplifier for Flexible Multimode MEMS-Referenced Oscillators. IEEE Transactions on Circuits and Systems I: Regular Papers, 2019, 66, 1405-1418.	3.5	8
97	Development of a Microfabricated Flat Interface Nerve Electrode Based on Liquid Crystal Polymer and Polynorbornene Multilayered Structures. , 2007, , .		7
98	Grain size control of (111) polycrystalline 3C-SiC films by doping used as folded-beam MEMS resonators for energy dissipation. Microsystem Technologies, 2009, 15, 875-880.	1.2	7
99	Environmentally-controlled Microtensile Testing of Mechanically-adaptive Polymer Nanocomposites for &lt;em>ex vivo</em> Characterization. Journal of Visualized Experiments, 2013, , e50078.	0.2	7
100	Direct, Transfer-Free Growth of Large-Area Hexagonal Boron Nitride Films by Plasma-Enhanced Chemical Film Conversion (PECFC) of Printable, Solution-Processed Ammonia Borane. ACS Applied Materials & Interfaces, 2018, 10, 43936-43945.	4.0	7
101	Probing heavy ion radiation effects in silicon carbide (SiC) via 3D integrated multimode vibrating diaphragms. Applied Physics Letters, 2019, 114, .	1.5	7
102	Inkjet-Printed Hydrogen Peroxide Sensor With Sensitivity Enhanced by Plasma Activated Inorganic Metal Salt Inks. Journal of Microelectromechanical Systems, 2020, 29, 1026-1031.	1.7	7
103	Behaviour of Polycrystalline SiC and Si Surface-Micromachined Lateral Resonant Structures at Elevated Temperatures. Materials Science Forum, 1998, 264-268, 889-894.	0.3	6
104	Fabrication and Characterization of Flexible, Microfabricated Neural Electrode Arrays Made from Liquid Crystal Polymer and Polynorbornene. Materials Research Society Symposia Proceedings, 2006, 926, 1.	0.1	6
105	Polycrystalline Diamond-on-Polymer Electrode Arrays Fabricated Using a Polymer-Based Transfer Process. Electrochemical and Solid-State Letters, 2010, 13, J129.	2.2	6
106	Removal of endotoxin from deionized water using micromachined silicon nanopore membranes. Journal of Micromechanics and Microengineering, 2011, 21, 054029.	1.5	6
107	Amorphous Silicon Carbide (<math>\pm</math>-SiC) Thin Square Membranes for Resonant Micromechanical Devices. Materials Science Forum, 2012, 717-720, 533-536.	0.3	6
108	Development of an Integrated Surface Stimulation Device for Systematic Evaluation of Wound Electrotherapy. Annals of Biomedical Engineering, 2015, 43, 306-313.	1.3	6

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109	Packaged capacitive pressure sensor system for aircraft engine health monitoring. , 2016, , .		6
110	Engineering the surface morphology of inkjet printed Ag by controlling solvent evaporation during plasma conversion of AgNO <sub>3</sub> inks. Journal of Materials Chemistry C, 2022, 10, 5257-5265.	2.7	6
111	A Reactive Inkjet Printing Process for Fabricating Biodegradable Conductive Zinc Structures. Advanced Engineering Materials, 2023, 25, .	1.6	6
112	Composition and physical properties of thin a-C:N and a-C:N:H films deposited by ion beam techniques. Surface and Interface Analysis, 1994, 21, 95-100.	0.8	5
113	Synthesis and Characterization of Nitrogen Containing Diamondlike Carbon Films made by ion Beam Deposition. Materials Research Society Symposia Proceedings, 1994, 349, 465.	0.1	5
114	On the stability of $\beta$ -SiC with respect to chemical disorder induced by irradiation with energetic particles. Philosophical Magazine Letters, 2001, 81, 55-61.	0.5	5
115	Characterization of Polycrystalline SiC Thin Films for MEMS Applications using Surface Micromachined Devices. Materials Science Forum, 2004, 457-460, 1523-1526.	0.3	5
116	Amorphous Silicon Carbide as a Non-Biofouling Structural Material for Biomedical Microdevices. Materials Science Forum, 0, 717-720, 537-540.	0.3	5
117	Wireless capacitive pressure sensor operating up to 400&#x00B0;c from 0 to 100 psi utilizing power scavenging. , 2014, , .		5
118	New developments in MEMS using SiC and TiNi shape memory alloy materials. Current Opinion in Solid State and Materials Science, 1997, 2, 566-570.	5.6	4
119	High-energy femtosecond pulsed laser micromachining of thin film deposited silicon in self-focused air medium. Journal of Laser Applications, 2002, 14, 221-229.	0.8	4
120	Young's Modulus and Residual Stress of Polycrystalline 3C-SiC Films Grown by LPCVD and Measured by the Load-Deflection Technique. Materials Science Forum, 2004, 457-460, 1519-1522.	0.3	4
121	Advanced Processing Techniques for Silicon Carbide MEMS and NEMS. Materials Science Forum, 2004, 457-460, 1451-1456.	0.3	4
122	Far-field detection of the super-lensing effect in the mid-infrared: theory and experiment. Journal of Modern Optics, 2005, 52, 2351-2364.	0.6	4
123	Nitrogen-Doping of Polycrystalline 3C-SiC Films Deposited by Low Pressure Chemical Vapor Deposition. Materials Science Forum, 2006, 527-529, 311-314.	0.3	4
124	Low Temperature A-SiC/Si Direct Bonding Technology for MEMS/NEMS. , 2007, , .		4
125	PVD silicon carbide as a thin film packaging technology for antennas on LCP substrates for harsh environments. , 2010, , .		4
126	Pressure dependence of thin polycrystalline silicon carbide diaphragm resonators. , 2012, , .		4



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127	A polycrystalline SiC-on-Si architecture for capacitive pressure sensing applications beyond 400 Â°C: Process development and device performance. Journal of Materials Research, 2013, 28, 120-128.	1.2	4
128	Development of polynorbornene as a structural material for microfluidics and flexible BioMEMS. Journal of Applied Polymer Science, 2014, 131, .	1.3	4
129	High frequency torsional-mode nanomechanical resonators enabled by very thin nanocrystalline diamond diaphragms. Diamond and Related Materials, 2015, 54, 19-25.	1.8	4
130	Materials Aspects of Micro- and Nanoelectromechanical Systems. Springer Handbooks, 2017, , 163-190.	0.3	4
131	Free-Standing Î²-Ga2O3 Thin Diaphragms. Journal of Electronic Materials, 2018, 47, 973-981.	1.0	4
132	Determination of Elastic Modulus of Silicon Carbide (SiC) Thin Diaphragms via Mode-Dependent Duffing Nonlinear Resonances. Journal of Microelectromechanical Systems, 2020, 29, 783-789.	1.7	4
133	A system to measure minute hydraulic permeability of nanometer scale devices in a non-destructive manner. Measurement Science and Technology, 2011, 22, 045802.	1.4	4
134	An Absorbent, Flexible, Transparent, and Scalable Substrate for Wound Dressings. IEEE Journal of Translational Engineering in Health and Medicine, 2022, 10, 1-9.	2.2	4
135	Silicon carbide micro- and nanoelectromechanical systems. , 2004, , .		3
136	Fabrication of hall device structures in 3C-SiC using microelectromechanical processing technology. Microelectronic Engineering, 2006, 83, 1396-1399.	1.1	3
137	PECVD Silicon Carbide as a Thin Film Packaging Material for Microfabricated Neural Electrodes. Materials Research Society Symposia Proceedings, 2007, 1009, 1.	0.1	3
138	Development of amorphous SiC for MEMS-based microbridges. , 2007, , .		3
139	Effects of biomedical sterilization processes on performance characteristics of MEMS pressure sensors. Biomedical Microdevices, 2007, 9, 809-814.	1.4	3
140	Additive Processes for Semiconductors and Dielectric Materials. MEMS Reference Shelf, 2011, , 37-136.	0.6	3
141	Fabrication and Characterization of MEMS-Based Structures from a Bio-Inspired, Chemo-Responsive Polymer Nanocomposite. Materials Research Society Symposia Proceedings, 2011, 1299, 1.	0.1	3
142	Silicon Carbide BioMEMS. , 2012, , 351-376.		3
143	3C-SiC microdisk mechanical resonators with multimode resonances at radio frequencies. Journal of Micromechanics and Microengineering, 2017, 27, 074001.	1.5	3
144	DEPOSITION TECHNIQUES FOR <font>SiC</font> MEMS. , 2006, , 18-45.		3

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145	Spatial Uniformity of the Mechanical Properties of 3C-SiC Films Grown on 4-Inch Si Wafers as a Function of Film Growth Conditions. Materials Science Forum, 1998, 264-268, 635-640.	0.3	2
146	Energy Dissipation in Folded-Beam MEMS Resonators Made from Single Crystal and Polycrystalline 3C-SiC Films. , 2007, , .		2
147	Silicon carbide MEMS oscillator. , 2009, , .		2
148	Material Aspects of Micro- and Nanoelectromechanical Systems. , 2010, , 333-356.		2
149	Temperature dependence of SiC thin film metal-insulator-metal (MIM) capacitors on alumina over a temperature range from 25 to 500°C. , 2011, , .		2
150	Focused Ion-Beam (FIB) Nanomachining of Silicon Carbide (SiC) Stencil Masks for Nanoscale Patterning. Materials Science Forum, 0, 717-720, 889-892.	0.3	2
151	A Low-Cost Automated Streaming Potential Measurement System. Journal of the Association for Laboratory Automation, 2012, 17, 125-133.	2.8	2
152	Diaphragm-based microsystems using thin film silicon carbide. , 2012, , .		2
153	(Invited) High Temperature Wireless Smart Sensor Technology Based on Silicon Carbide Electronics. ECS Transactions, 2014, 61, 127-138.	0.3	2
154	Electrical interfaces for recording, stimulation, and sensing. , 2015, , 13-38.		2
155	Demonstration of a Packaged Capacitive Pressure Sensor System Suitable for Jet Turbofan Engine Health Monitoring. , 2016, , .		2
156	Correlating charge fluence with nanoparticle formation during in situ plasma synthesis of nanocomposite films. Plasma Processes and Polymers, 2017, 14, 1700079.	1.6	2
157	Energetic ion radiation effects on a silicon carbide (SiC) multimode resonating diaphragm. , 2017, , .		2
158	An Inkjet Printed Ag Strain Gauge on Flexible Cellophane using a Metal-Salt based Ink. , 2021, , .		2
159	Finite-Element Modeling of Residual Stress in SiC Diaphragms. Materials Research Society Symposia Proceedings, 1998, 518, 221.	0.1	1
160	Mechanical Properties and Morphology of Polycrystalline 3C-SiC Films Deposited on Si and SiO <sub>2</sub> by LPCVD. Materials Research Society Symposia Proceedings, 2003, 795, 140.	0.1	1
161	A Polynorbornene-Based Microelectrode Array for Neural Interfacing. , 2007, , .		1
162	Long-term thermal mechanical stability of PECVD amorphous silicon carbide films for harsh environment microelectromechanical systems. , 2013, , .		1

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163	Polycrystalline diamond circular resonant diaphragms with low onset of nonlinear response. , 2013, , .		1
164	Doped polycrystalline 3C-SiC films with low stress for MEMS: part II. Characterization using micromachined structures. Journal of Micromechanics and Microengineering, 2014, 24, 065001.	1.5	1
165	Doped polycrystalline 3C-SiC films with low stress for MEMS: part I. Deposition conditions and film properties. Journal of Micromechanics and Microengineering, 2014, 24, 035013.	1.5	1
166	Wide bandgap $\text{In}^2\text{-Ga}_2\text{O}_3$ nanomechanical resonators for detection of middle-ultraviolet (MUV) photon radiation. , 2017, , .		1
167	An improved tactile sensing device for material characterization via friction-induced vibrations. Sensors and Actuators A: Physical, 2020, 303, 111824.	2.0	1
168	Wireless Monitoring of Vascular Pressure Using CB-PDMS Based Flexible Strain Sensor. , 2021, 2021, 7011-7015.		1
169	Micromachining techniques for silicon carbide MEMS. , 1999, , .		0
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